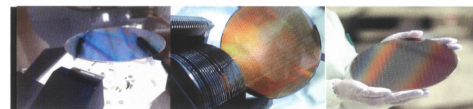


The Development and the commercialization of the Mask Aligner for wafer  
Midas System will continue to grow along with the value creation for our customers.

<http://www.aligner.co.kr>

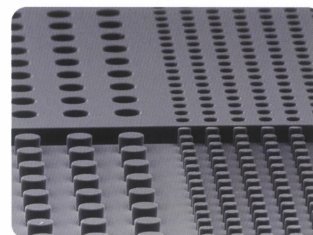
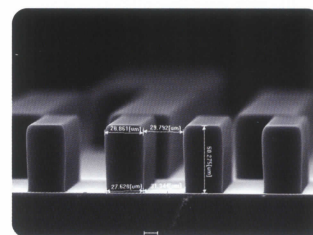
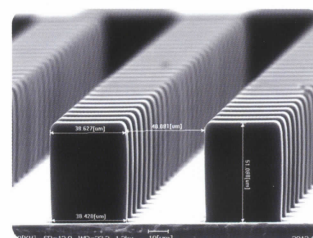
# **MDA-80SA**



The MDA-80SA is a brand new model and represents next generation of Full-field lithography systems. This brand new Semi-auto Aligner platform offers a higher Overlay Accuracy and more reliable operation. Joystick control and touch panel is more easy to access in your process.



▼ SEM Image



ITEM	SPECIFICATIONS
Substrate Size	Up to 8 inch
UV Lamp Power	2 kW
Resolution	1 $\mu$ m with 1 $\mu$ m thin PR @ Si wafer
Alignment Accuracy	1 $\mu$ m
Lamp Uniformity	$\leq \pm 5\%$
Uniform Beam Size	9.25" $\times$ 9.25"
365nm Beam Intensity	15~20mW/cm <sup>2</sup>
Exposure Time	0.1 ~ 999.9 sec
Motorized	Microscope X, Y -axis, Zoom and Focus Stage X, Y, $\theta$ and Z-axis
Process mode	Vacuum, Hard, Soft and Proximity
Dimension	1,500 $\times$ 1,500 $\times$ 1,900 mm



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